



Atty. Dkt. No. AMAT/6493/ETCH/SILICON/JB1

In re Application of:  
Nallan, et al.

Serial No.: 09/993,240

Confirmation No.: 6869

Filed: November 13, 2001

**For: Apparatus for Controlling a Thermal Conductivity Profile for a Pedestal in a Semiconductor Wafer Processing Chamber**

**MAIL STOP RCE**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

Group Art Unit: 1763

Examiner: Ram N. Kackar

CERTIFICATE UNDER 37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on March 11, 2004 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV335477743US addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

Signature

Date \_\_\_\_\_

Signature \_\_\_\_\_

**Dear Sir:**

## REQUEST FOR NON-ENTRY OF AMENDMENT

Applicants respectfully request non-entry of the Response to the November 20, 2003 Final Office Action mailed on January 20, 2004.

Respectfully submitted,

Bei hantzen

**Ari Pramudji**

Registration No. 45,022

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